## POROUS ADHESIVE SHEET, SEMICONDUCTOR WAFER WITH POROUS ADHESIVE SHEET, AND METHOD OF MANUFACTURE THEREOF

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## Abstract of WO0151580

A porous adhesive sheet (1) comprises adhesive organic film (3), in which a plurality of parallel through holes extend along the film thickness (A) between opposite ends (2a, 2b). The through holes have similar cross sections. A semiconductor wafer (31) provided with a porous adhesive sheet is manufactured using a semiconductor wafer (32) to which a porous adhesive sheet (1) is attached such that through holes (2) aligned with electrodes (33) on the wafer are filled with conductive material to form conductors (34).

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